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# Index

## A

- Advanced Planning System (APS), 10, 248
- Advanced Process Control (APC), 250, 263
- agent, 9
  - decision-making, 257
  - staff, 257
- assembly, 12, 25
- Automated Material Handling System (AMHS), 10, 19, 155
- Available-to-Promise (ATP), 265

## B

- back-end, 12
- base process (BP), 14
- base system (BS), 13
- batch, 16, 106
- batching
  - parallel, 107
  - serial, 106
- batching rule, 79
  - Batched Apparent Tardiness Cost (BATC) rule, 80, 91
- Dynamic Batching Heuristic (DBH), 81
- Full Batch Policy (MBSF), 80
- Greedy Batch Policy (MBSP), 80
- look-ahead, 81
- Minimum Batch Size (MBS), 80
- Minimum Cost Rate (MCR), 90
- Next Arrival Control Heuristic (NACH), 84
- beam search, 34, 119
- binning, 26
- blackboard-type data layer, 62, 98, 163, 254

## branch-and-bound, 33

- buffer, 15
- burn-in, 26

## C

- Capable-To-Promise (CTP), 265
- Capacity Allocation Routine (CAR), 143
- capacity planning, 219
  - short term, 207
- chip, 1, 11
- clearing function, 241
  - allocated (ACF), 243
- cluster tool, 16
  - external scheduling, 107
  - internal scheduling, 107
- control process (CP), 14
- control system (CS), 14
- cycle time (CT), 41
  - average, 56
  - load-dependent, 231
- cycle time throughput curve, 231

## D

- delayed precedence constraint, 157
- design of experiments, 60
- desirability function approach, 58
- diffusion, 20
- disjunctive graph, 149
- dispatching, 27
- dispatching rule, 65
  - Apparent Tardiness Cost (ATC), 75
  - Apparent Tardiness Cost with Setups (ATCS), 76
- automated discovery, 101
- blended, 98
- composite, 66, 74

dispatching rule (*cont.*)  
 Critical Ratio (CR), 74  
 Earliest Due Date (EDD), 68  
 Farthest Job First (FJF), 73  
 Fewest Lots in the Next Queue (FLNQ), 69  
 First-In-First-Out (FIFO), 42, 68  
 Flow Control (FC), 70  
 Global ATCS (GATCS), 97  
 Highest Value First (HVF), 69  
 Last-In-First-Out (LIFO), 42  
 Least Setup Cost (LSC), 70  
 Least Slack (LS), 70  
 Line Balance (LB), 100  
 Longest Processing Time (LPT), 69  
 Longest Waiting Time (LWT), 73  
 look-ahead, 66, 81  
 Nearest Job First (Njf), 73  
 Operational Due Date (ODD), 68  
 Shortest Processing Time (SPT), 68  
 Shortest Remaining Processing Time (SRPT), 69  
 Weighted Shortest Processing Time (WSPT), 69  
 dispatching system, 253  
 due date, 23  
 dynamic programming, 37

**E**

Enterprise Resource Planning (ERP) system, 264  
 enterprise-wide semiconductor planning, 222  
 Equipment Engineering System (EES), 263  
 Equipment Management and Maintenance System (EMMS), 263  
 etch, 21

**F**

Fault Detection and Classification (FDC), 263  
 film deposition, 20  
 final test, 25  
 first-fit decreasing (FFD) heuristic, 144, 147  
 flow shop, 21  
 flexible, 25, 106  
 reentrant, 25  
 fluctuation smoothing policy, 70  
 Mean Cycle Time (FSMCT), 71  
 Variance of Cycle Time (FSVCT), 71  
 Variance of Lateness (FSVL), 71  
 front-end, 12

Front-Opening Unified Pod (FOUP), 10  
 full factory scheduling, 149

**G**

genetic algorithm (GA), 40, 126, 219  
 grouping (GGA), 148  
 genetic programming (GP), 103

**H**

handler, 26  
 heuristic, 33

**I**

incompatible job family, 22, 79, 110, 131  
 inductive decision tree, 54  
 infinite capacity approach (ICA), 167, 256  
 information system (IS), 13  
 integrated circuit (IC), 1  
 interbay system, 18  
 intrabay system, 18  
 ion implantation, 21

**J**

job, 12  
 job processing system (JS), 13  
 job shop, 21  
 complex, 25, 106  
 flexible, 25, 106  
 reentrant, 25

**K**

Kingman diffusion approximation, 43

**L**

lateness, 57  
 layer, 11, 20  
 learning system, 53  
 linear programming (LP), 35  
 Little's Law, 42  
 load board, 18  
 load lock, 16  
 load port, 19, 24  
 local search, 39, 135  
 lot, 12

**M**

machine, 13  
 batch processing, 16  
 dedication, 17  
 single, 15, 106  
 state, 15  
 machine breakdown  
 time-to-failure (TTF), 45  
 time-to-repair (TTR), 45  
 makespan, 56, 119, 124

- Manufacturing Execution System (MES), 7, 248, 251
- manufacturing resources planning (MRP II), 264
- mask, 18, 20
- master planning, 215, 265
- Material Control System (MCS), 10, 28, 263
- material flow system (MS), 13
- material requirements planning (MRP), 178, 264
- metaheuristic, 38, 50
- mixed integer programming (MIP), 34
- model, 30
- decision, 32
  - descriptive, 31
  - deterministic, 31
  - dynamic, 31
  - optimization, 32
  - prescriptive, 31
  - static, 31
  - stochastic, 31
- multi-agent-system, 10, 260, 262
- Multiple Orders per Job (MOJ), 107, 144
- lot processing, 145
  - single item processing, 145
- N**
- neighborhood
- search, 38
  - structure, 38
- neural network, 53
- O**
- operation, 20
- operational system (OS), 14
- optimization
- discrete, 33
  - simulation-based, 50
- order release, 27, 177
- optimization-based, 196
  - simulation-based, 193
- Overall Equipment Effectiveness (OEE), 254
- Overhead Hoist Transportation (OHT), 19
- Overhead Hoist Vehicle (OHV), 19
- oxidation, 20
- P**
- parallel machine, 106
- identical, 106
  - unrelated, 106
- Pareto optimality, 170
- performance assessment, 55
- scheme, 55
  - simulation-based, 62
- photolithography, 20
- pipelining, 24
- planarization, 21
- planning process (PP), 14
- planning system (PS), 14
- priority index, 66
- probe, 11
- process flow, 14, 21
- process step, 14, 20
- processing time, 21
- family-dependent, 22
  - sequence-dependent, 107
- Product Resource Order Staff Architecture (PROSA), 256
- production planning, 26, 231
- production planning and control (PPC) hierarchy, 27
- pull approach, 178
- push approach, 178
- Q**
- queueing theory
- Kendall notation, 43
  - network, 43
  - system, 41
- R**
- ready time, 106, 132, 138
- Real Time Dispatcher (RTD), 253
- recipe, 14, 24
- reentrant flow, 21, 22
- rescheduling, 166
- resource, 13, 27
- auxiliary, 14, 18
  - secondary, 14
- response surface, 52
- reticle, 18, 138, 143
- rework, 21
- rule-based system, 94, 253
- S**
- scheduling, 27, 105
- deterministic, 105
  - list, 67, 162
  - multicriteria, 169
  - notation scheme, 106
  - simulation-based, 108
  - system, 255
- send-ahead wafer, 142, 143
- sequence-dependent setup time, 23, 123

- service oriented architecture (SOA), 250  
 shifting bottleneck heuristic (SBH), 156  
     distributed (DSBH), 166, 256  
 machine criticality measure, 159, 160  
 reoptimization, 160  
 subproblem, 157  
 subproblem solution procedure (SSP),  
     159  
 simulated annealing (SA), 39  
 simulation, 44  
     continuous, 44  
     discrete-event, 44  
     iterative, 51, 239  
 sort, 11  
 Starvation Avoidance (SA), 180  
 Statistical Process Control (SPC), 263  
 stepper, 20, 131, 142, 143  
 stochastic programming, 35, 221, 230  
 stocker, 18  
 supply network planning, 26, 265  
 system, 13
- T**  
 tabu search, 40, 140  
 tardiness, 57  
 technology, 21
- tester, 26  
 throughput (TP), 56  
 time constraints, 23  
 time window decomposition heuristic  
     (TWDH), 134
- U**  
 Under Track Storage (UTS), 19
- V**  
 variable neighborhood search (VNS), 40,  
     135  
 Virtual Metrology (VM), 263
- W**  
 wafer, 1, 11  
 wafer fabrication, 2  
 work area, 15, 166  
 work center, 15  
 work-in-process (WIP), 42  
 working object, 14  
 Workload Regulation (WR), 181
- Y**  
 yield, 21